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CONFIRMATION NO. 4607

<b>SERIAL NUMBER</b> 10/512,405	<b>FILING OR 371(c) DATE</b> 06/15/2005 <b>RULE</b>	<b>CLASS</b> 438	<b>GROUP ART UNIT</b> 2812	<b>ATTORNEY DOCKET NO.</b> 474082002800
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## APPLICANTS

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## \*\* CONTINUING DATA \*\*\*\*\*

This application is a 371 of PCT/JP03/04866 04/16/2003

## \*\* FOREIGN APPLICATIONS \*\*\*\*\*

JAPAN 2002-127509 04/26/2002  
 JAPAN 2002-360731 12/12/2002

Foreign Priority claimed

☒ yes ☐ no

35 USC 119 (a-d) conditions met

☒ yes ☐ no ☐ Met after

Verified and Acknowledged

Examiner's Signature

Initials

**STATE OR COUNTRY**  
JAPAN

**SHEETS DRAWING**  
6

**TOTAL CLAIMS**  
17

**INDEPENDENT CLAIMS**  
4

## ADDRESS

25227

## TITLE

High resistance silicon wafer and method for production thereof

**FILING FEE RECEIVED**  
1594

FEES: Authority has been given in Paper  
 No. \_\_\_\_\_ to charge/credit DEPOSIT ACCOUNT  
 No. \_\_\_\_\_ for following:

☐ All Fees

☐ 1.16 Fees ( Filing )

☐ 1.17 Fees ( Processing Ext. of time )

☐ 1.18 Fees ( Issue )

☐ Other \_\_\_\_\_

☐ Credit